Accepted Manuscript

Title: The importance of pressure and mass ratios when depositing multi-element oxide thin films by pulsed laser deposition

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PII: S0169-4332(16)31428-3

DOI: http://dx.doi.org/doi:10.1016/j.apsusc.2016.07.003

Reference: APSUSC 33569

To appear in: APSUSC

Received date: 1-4-2016 Revised date: 6-6-2016 Accepted date: 1-7-2016

Please cite this article as: Alejandro Ojeda-GP, Christof W.Schneider, Max Döbeli, Thomas Lippert, Alexander Wokaun, The importance of pressure and mass ratios when depositing multi-element oxide thin films by pulsed laser deposition, Applied Surface Science http://dx.doi.org/10.1016/j.apsusc.2016.07.003

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